



Attorney Docket No. 033082 M 300

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:

Yasuo KOBAYASHI, et al.

International Application No.: PCT/JP 2004/011595 Group Art Unit: 2812

International Filing Date: August 12, 2004

Examiner: Reema Patel

Serial No.: 10/568,461

Filed: February 15, 2006

For : SEMICONDUCTOR DEVICE, MANUFACTURING METHOD OF
SEMICONDUCTOR DEVICE, AND GAS FOR PLASMA CVD PROCESS

FOURTH INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to the duty of disclosure under 37 C.F.R. 1.56, Applicants are enclosing an Information Disclosure Citation Form (PTO-1449) which lists the documents noted in the Supplementary European Search Report being submitted herewith.

Applicants certify under 37 C.F.R. 1.97(e)(1) that each item of information contained in the information disclosure statement was first cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the information disclosure statement.



It is respectfully requested that the cited documents be considered by the Examiner in the above-identified patent application, that they be made officially of record therein and that a listing of same appear on the face of any patent which may issue in this application.

Respectfully submitted,

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